Update Search

## **EAST Search History**

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L17	287	(sharma near3 manish).in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/16 12:07
L18	292	(heon near3 lee).in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/16 12:07
L20	3534	(magnetic adj tunnel\$3 adj junction\$1)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/16 12:10
L22	630	(resistivit\$3) same ((oxidat\$4 oxidiz\$6 nitrid\$6 carburiz\$6) with plasma\$1)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/16 12:11
L23	9	20 and 22	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/16 12:13
L24	1	(17 18) and 22	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/16 12:13

Interference Search

## **EAST Search History**

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L12	1488	(magnetic adj tunnel\$3 adj junction\$1)	US-PGPUB	OR	OFF	2006/11/16 11:41
L13	23	12 same ((oxidat\$4 oxidiz\$6 nitrid\$6 carburiz\$6) with plasma\$1)	US-PGPUB	OR	OFF	2006/11/16 11:42
L14	1	13 same (high near5 resistivit\$3) with (electrode\$1)	US-PGPUB	OR	OFF	2006/11/16 11:43



Day: Thursday Date: 11/16/2006 Time: 12:06:15

## **Inventor Name Search Result**

Your Search was:

Last Name = SHARMA First Name = MANISH

<b></b>					
Application#					Inventor Name
08111002	5390017	150	08/24/1993	OPTICAL NETWORK ANALYZER FOR MEASURING THE AMPLITUDE CHARACTERISTIC AND GROUP DELAY TIME DISPERSION CHARACTERISTICS OF AN OPTICAL CIRCUIT DEVICE	SHARMA, MANISH
08211717	5432602	150	04/25/1994	LIGHT WAVELENGTH MEASURING APPARATUS WITH LIGHT MODULATION	SHARMA, MANISH
08389504	5717795	250	02/16/1995	OPTICAL WAVELENGTH DIVISION MULTIPLEXED NETWORK SYSTEM	SHARMA, MANISH
08479012	5839103	150	06/07/1995	SPEAKER VERIFICATION SYSTEM USING DECISION FUSION LOGIC	SHARMA, MANISH
<u>08697446</u>	5739943	150	08/23/1996	POLARIZATION CONTROL UNIT	SHARMA, MANISH
08777203	5918518	150		APPARATUS AND METHOD FOR CUTTING WEB	SHARMA, MANISH
08813590	6081355	150	1	MULTI-WAVELENGTH LIGHT SOURCE	SHARMA, MANISH
08827562	<u>5862519</u>	150	04/01/1997	BLIND CLUSTERING OF DATA WITH APLICATION TO SPEECH PROCESSING SYSTEMS	SHARMA, MANISH
08976279	Not Issued	161	11/21/1997	USER VALIDATION FOR INFORMATION SYSTEM ACCESS AND TRANSACTION PROCESSING	SHARMA, MANISH
08976280	6539352	150		SUBWORD-BASED SPEAKER VERIFICATION WITH MULTIPLE- CLASSIFIER SCORE FUSION WEIGHT AND THRESHOLD ADAPTATION	SHARMA, MANISH
09015393	6480825	150	1 1	SYSTEM AND METHOD FOR DETECTING A RECORDED VOICE	SHARMA, MANISH
09210712	6058817	150		APPARATUS AND METHOD FOR CUTTING WEB	SHARMA, MANISH
<u>09441602</u>	6304622	150	l I	FLEXIBLE BIT RATE CLOCK RECOVERY UNIT	SHARMA, MANISH
09634370	Not	161	08/09/2000	Positively chirped signals in optical	SHARMA, MANISH



Day: Thursday Date: 11/16/2006 Time: 12:06:00

## Inventor Name Search Result

Your Search was:

Last Name = LEE

First Name = HEON

Application#	Patent#	Status	Date Filed	Title	Inventor Name
08994265	6012550	150	12/19/1997	BYPASS DEVICE FOR AUTOMATIC TRANSMISSION FLUID PROVIDED WITH A THERMAL EXPANSION BAR	LEE, HEON
08998786	6089735	150	12/29/1997	EASY-EXCHANGEABLE HEAD LAMP FOR AUTOMOBILES	LEE, HEON
09172456	6228277	150	10/14/1998	ETCH ENDPOINT DETECTION	LEE, HEON
09374537	6355520	150		METHOD FOR FABRICATING 4F2 MEMORY CELLS WITH IMPROVED GATE CONDUCTOR STRUCTURE	LEE, HEON
09374538	6294436	150	08/16/1999	METHOD FOR FABRICATION OF ENLARGED STACKED CAPACITORS USING ISOTROPIC ETCHING	LEE, HEON
09383666	6352934	150	08/26/1999	SIDEWALL OXIDE PROCESS FOR IMPROVED SHALLOW JUNCTION FORMATION IN SUPPORT REGION	LEE, HEON
09460318	6362033	150	12/14/1999	SELF-ALIGNED LDD FORMATION WITH ONE-STEP IMPLANTATION FOR TRANSISTOR FORMATION	LEE, HEON
09489771.	6214661	150		Method to prevent oxygen Out-Diffusion from BSTO containing Micro-Electronic device	LEE, HEON
09489865	6261924	150	01/21/2000	Maskless process for self-aligned contacts	LEE, HEON
09583963	<u>6284666</u>	150	1	Method of reducing RIE lag for deep trench silicon etching	LEE, HEON
09596484	Not Issued	162		METHOD TO ETCH POLY SI GATE STACKS WITH RAISED STI STRUCTURE	LEE, HEON
09599703	6326260	150		Gate prespacers for high density high performance drams	LEE, HEON
09608565	Not Issued	161		Method of etching noble metals using ion implantation	LEE, HEON
09609472	Not Issued	161	06/30/2000	CONCAVE SHAPED STACK CAPACITOR	LEE, HEON
09660679	Not	161	09/13/2000	Apparatus for etching noble metals using	LEE, HEON